## **AMENDMENTS TO THE CLAIMS**

This listing of claims will replace all prior versions, and listings, of claims in the application:

## **Listing of Claims:**

1	1. (Currently amended) A microrelay, comprising:
2	a first signal line;
3	a second signal line;
4	a contact head configured to make an electrical connection between the
5	first signal line and the second signal line; and
6	an electro-thermal actuator coupled to the contact head and configured to
7	laterally displace the contact head so that the closing action of the contact head is
8	parallel to the plane of a semiconductor wafer upon which the microrelay is
9	fabricated;
10	wherein the contact head and associated portions of the first and second
11	signal lines are covered with a layer of sputtered gold, and wherein a partial
12	release operation was performed at the closing gap to ensure the separation of
13	sputtered gold on the contact head sidewall and the signal lines.
1	2. (Original) The microrelay of claim 1,
2	wherein the electro-thermal actuator comprises a substantially V-shaped
3	beam;
4	wherein thermal expansion caused by current flowing through the
5	substantially V-shaped beam actuates the contact head to make the electrical
6	connection.

3. (Original) The microrelay of claim 1, wherein the electro-thermal
actuator comprises a substantially V-shaped central beam cascaded between two
substantially V-shaped side beams, which increase the displacement of the
substantially V-shaped central beam during actuation.
4. (Original) The microrelay of claim 1, wherein the electro-thermal
actuator is comprised of:
silicon;
polysilicon;
nickel; or
tungsten.
5 (01-1)
5 (Canceled).
6. (Original) The microrelay of claim 1, wherein the contact head is
coupled to the electro-thermal actuator through an insulator.
7. (Original) The microrelay of claim 6, wherein the insulator is comprised
of:
silicon nitride; or
silicon dioxide.
8 (Canceled).
9. (Currently amended) The microrelay of claim 1, wherein the shape of
the contact head is:
square;
<del>angled;</del> or

5	rounded.
J	Tourided.

1	10. (Original) The microrelay of claim 1, wherein the microrelay is
2	fabricated using a process that involves:
3	deposition of low-stress silicon nitride as isolation;
4	deposition and patterning of sacrificial silicon dioxide;
5	deposition and patterning of a low-stress silicon nitride connection;
6	deposition and patterning of polysilicon;
7	a partial release operation;
8	sputtering and lift-off of gold; and
9	a full release operation.
1	11. (Original) The microrelay of claim 1, wherein the microrelay is an
2	element in an array of microrelays.
1	12. (Currently amended) A microrelay, comprising:
2	a first signal line;
3	a second signal line;
4	a contact head configured to make an electrical connection between the
5	first signal line and the second signal line; and
6	an electro-thermal actuator coupled to the contact head and configured to
7	laterally displace the contact head so that the closing action of the contact head is
8	parallel to the plane of a semiconductor wafer upon which the microrelay is
9	fabricated;
10	wherein the electro-thermal actuator comprises a substantially V-shaped
11	beam, wherein thermal expansion caused by current flowing through the
12	substantially V-shaped beam actuates the contact head to make the electrical
13	connection;

wherein the contact head and associated portions of the first and second 14 signal lines are covered with a layer of sputtered gold, and wherein a partial 15 release operation was performed at the closing gap to ensure the separation of 16 sputtered gold on the contact head sidewall and the signal lines. 17 13 (Canceled). 1 14. (Original) The microrelay of claim 12, wherein the contact head is 1 2 coupled to the electro-thermal actuator through an insulator. 15 (Canceled). 1 16. (Currently amended) The microrelay of claim 12, wherein the shape of 1 2 the contact head is: 3 square; 4 angled; or 5 rounded.

17-20 (Canceled).

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